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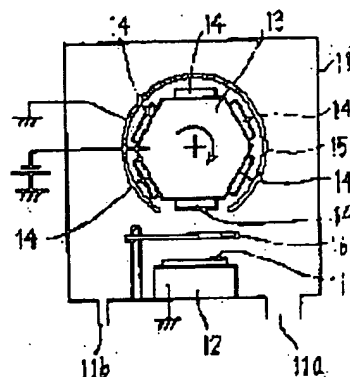
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(54) SPUTTERING DEVICE

(57)Abstract:

PURPOSE: To continuously form plural thin films constituted of different kinds of materials in the same vacuum vessel in the structure of a sputtering device.

CONSTITUTION: The inside of a vacuum vessel 11 is provided with a prismatic target holder 13 supported rotatably in a vacuum vessel 1. Plural target plates 14 are fixed along the outer circumference of the target holder 13. One piece among them is opposed against a substrate 1 arranged in the vacuum vessel 11 and the materials of the target plates 14 are formed on the substrate 1.



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